

High power femtosecond laser sources at 1030nm, 515nm and 343nm for cutting-edge solutions

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28 June 2023 - EPIC Meeting on Ultrafast Laser Processing



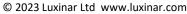






LXR[®] ultrashort pulse lasers

Parameter	LXR [®] 120-1030	LXR [®] 50-1030	LXR [®] 80-515	LXR [®] 40-343
Wavelength	1030nm	1030nm	515nm	343nm
Rated average power	120W	50W	80W	40W
Pulse duration	800 ± 100fs			900 ± 100fs
Rated pulse energy	120µJ	100µJ	80µJ	40µJ
Max. fast burst energy	لىر006	250µJ	400µJ	200µJ
Frequency	Single shot to 40MHz			
Power and pulse energy stability	< ± 1%rms			
Polarisation	Linear perpendicular to base			
Typical beam quality	M ² < 1.2			M ² < 1.3
Output beam diameter	3mm ± 0.5mm			
a 2022 Luvinar Ltd. ywyy luvinar com				



LXR is a registered trademark (in the UK, EU and elsewhere) owned (in the UK, EU and elsewhere) by Luxinar Ltd, and must not be used without permission from the owner

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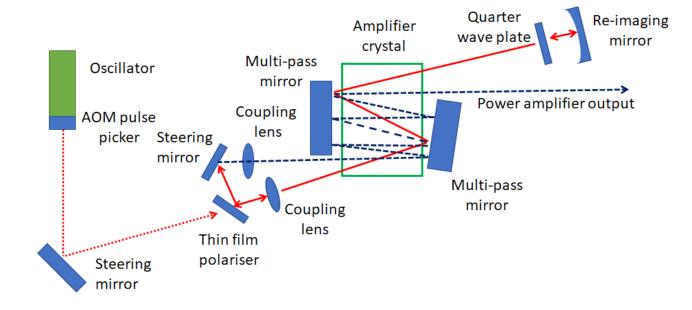


LXR* 120-1030



LXR[®] ultrashort pulse lasers: patented technology

- Pre-amplifier and power amplifier in one crystal
- Demonstrated input seed powers of 15mW 3W resulting in similar amplified output powers

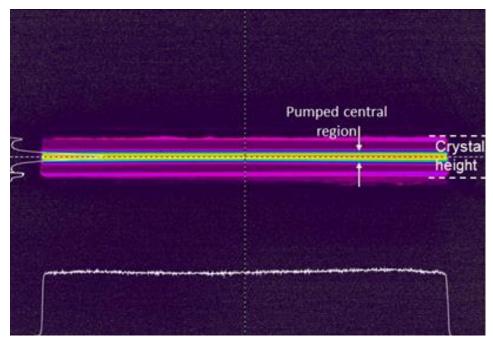


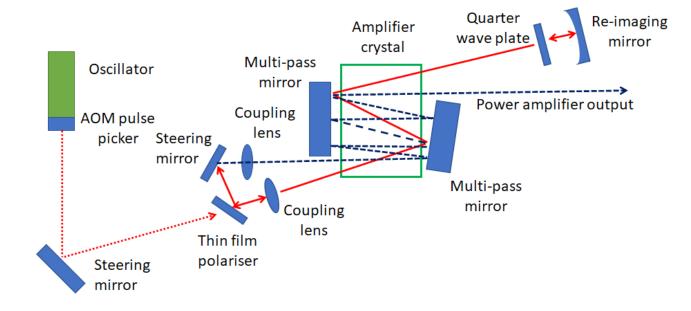




LXR[®] ultrashort pulse lasers: patented technology

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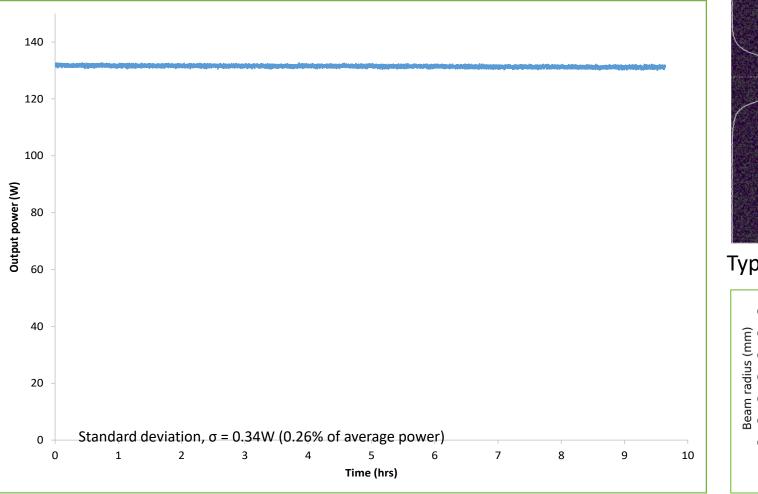
High intensity and uniform gain region for effective amplification²

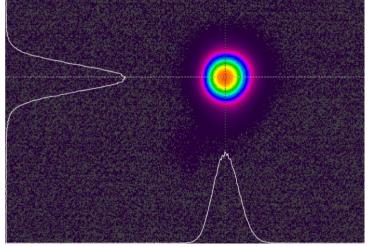


Patent number US9306366B2
Patent number US9847616

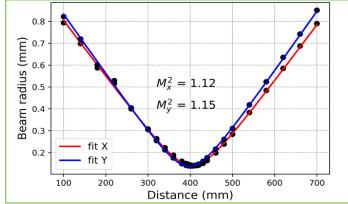


LXR[®] 120-1030





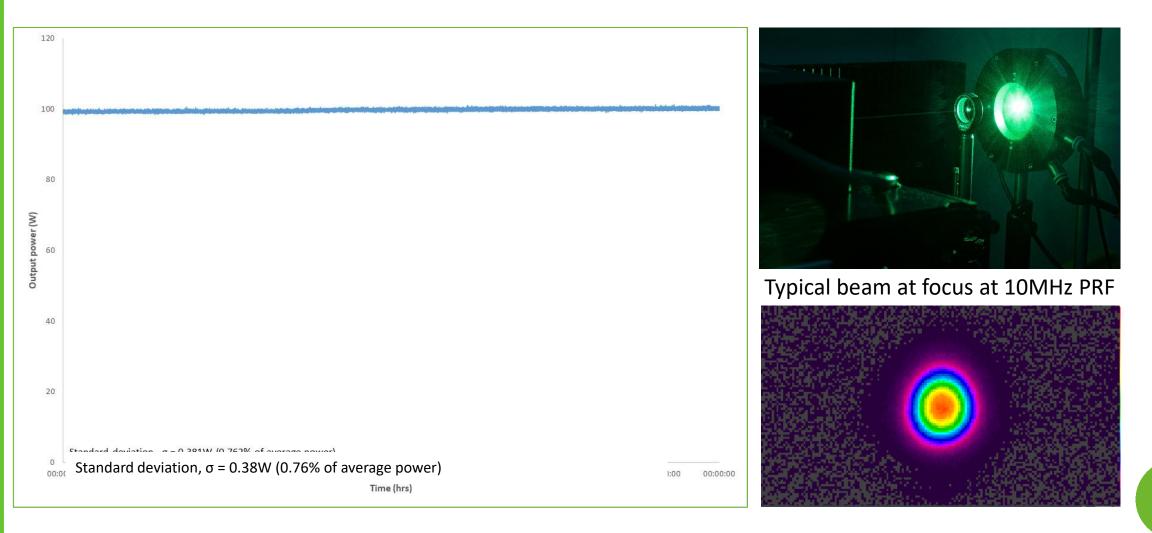
Typical beam at focus and caustic plot





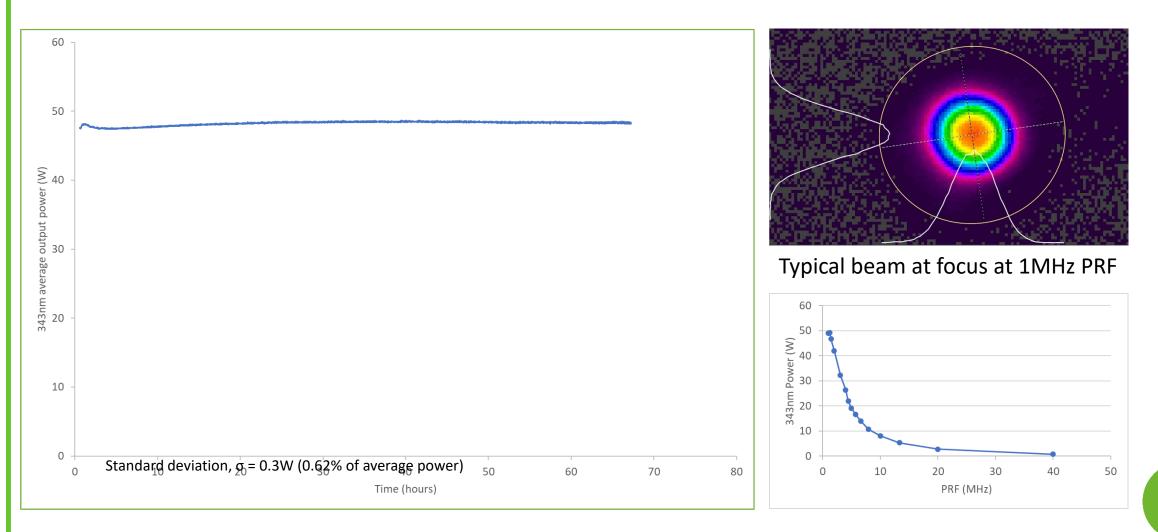


LXR[®] 80-515





LXR[®] 40-343





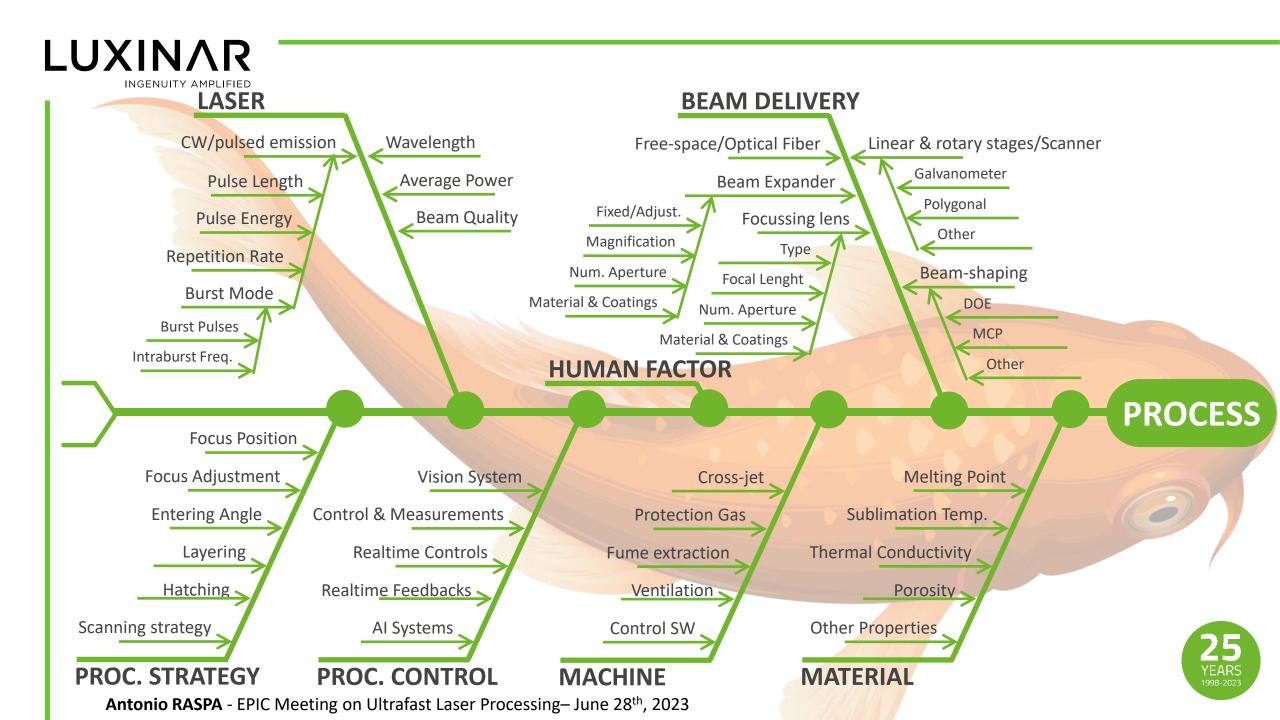
WHY

... we need this complexity ?

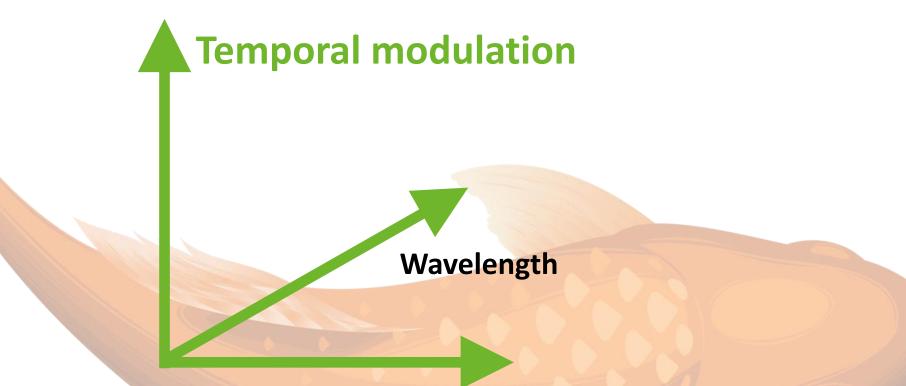
... we must pay for it?



Wait until the mud settles and the water is clear Lao Tzu



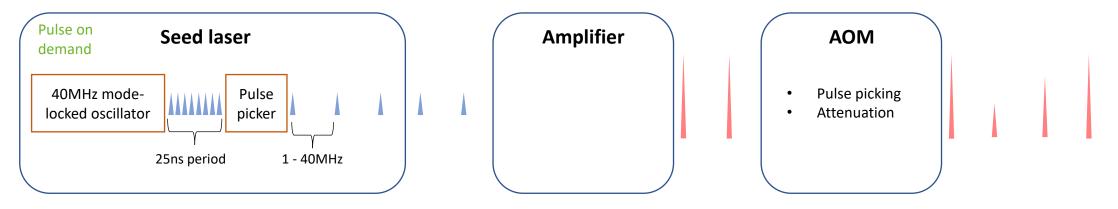




Spatial Beam Shaping

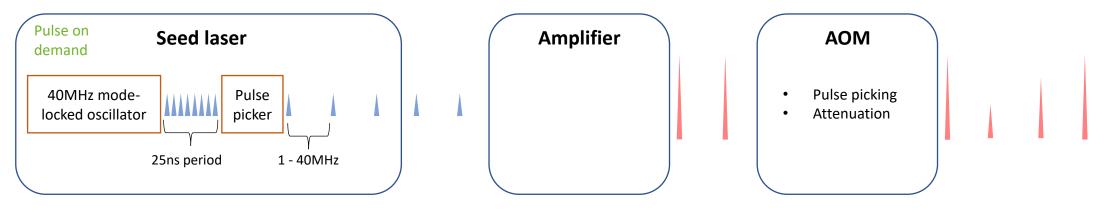








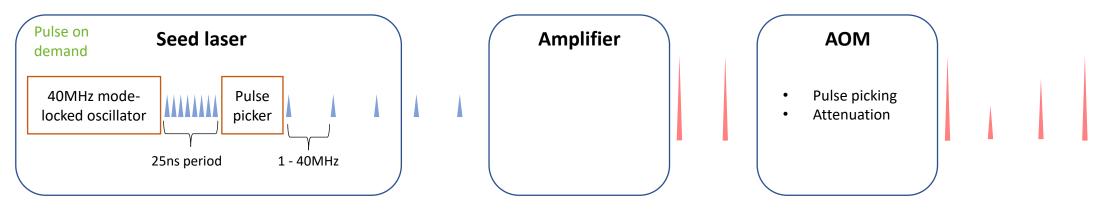




- Sync output available which allows the user/scanner to synchronise *exactly* with the laser output
- Pulse energy can be maintained to ±1% whether 10 kHz is requested or 10 MHz is requested

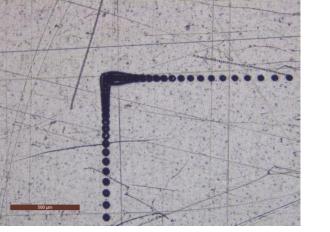


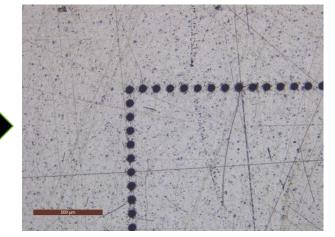




- Sync output available which allows the user/scanner to synchronise *exactly* with the laser output
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No pulse on demand with 100µm spacing



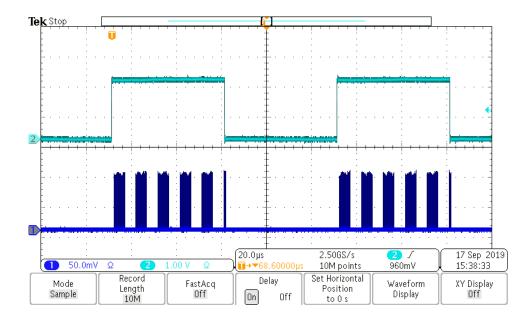


Pulse on demand with 100µm spacing





- Laser can be programmed to operate bursts as well as gated
- Individual pulse energy can be set within these bursts up to 10 MHz

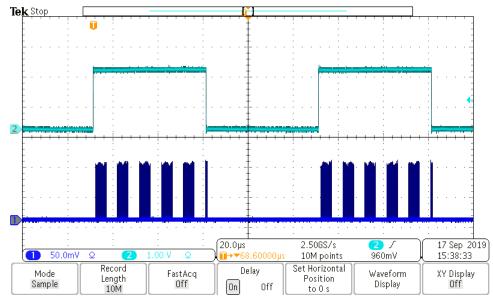


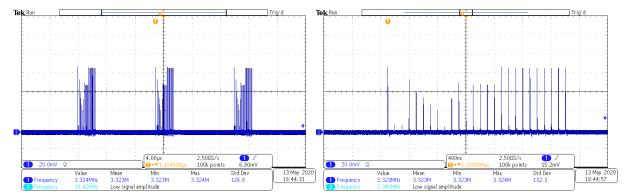
- Intraburst frequency 10MHz
- 50 pulses per burst
- Burst frequency 100kHz
- Gating frequency 10kHz





- Laser can be programmed to operate bursts as well as gated
- Individual pulse energy can be set within these bursts up to 10 MHz





- Intraburst frequency 10MHz
- 50 pulses per burst
- Burst frequency 100kHz
- Gating frequency 10kHz





2.50GS/s 100k points

Max 9.963M

Value 9.962MHz Mean 9.962M Min 9.962M 15.2mV

13 May 2020 18:49:06 Value 9.962MHz

quency

Mean 9.962M Min 9.959M

Std Dev 713.6 100k points

2.50GS/s 100k points

Max 9.967M 15.2mV

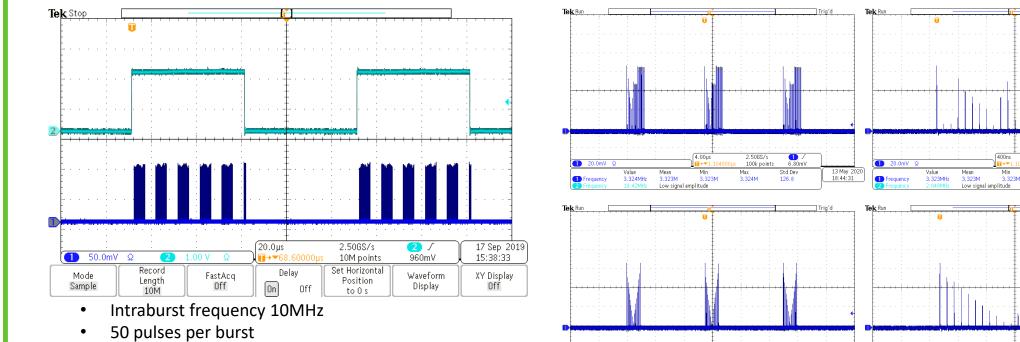
Std Dev 1.687k

15.2mV

13 May 2020 18:44:57

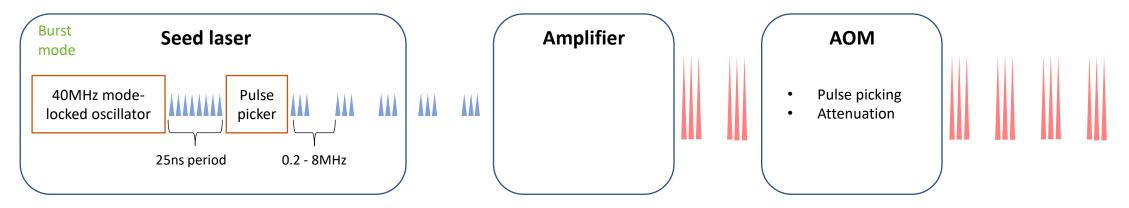
Std Dev 132.3

- Laser can be programmed to operate bursts as well as gated
- Individual pulse energy can be set within these bursts up to 10 MHz



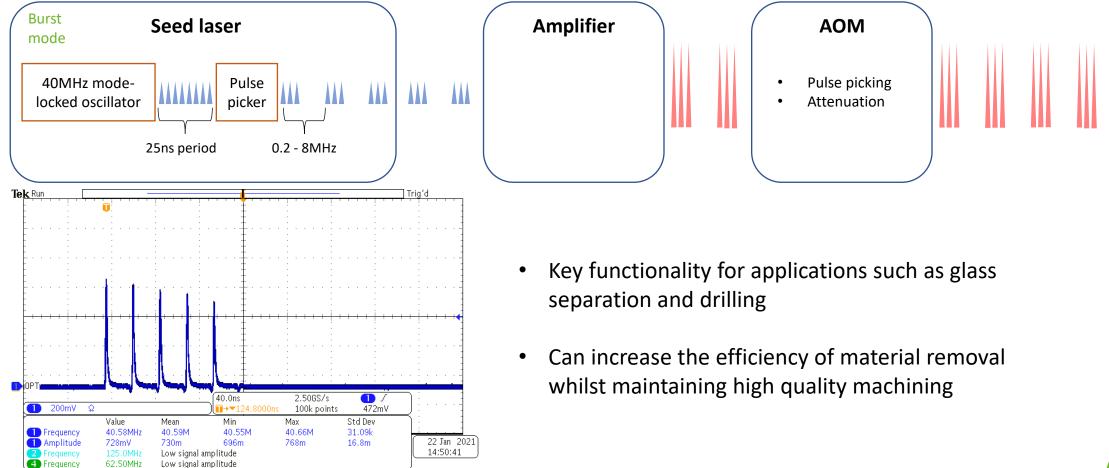
- Burst frequency 100kHz
- Gating frequency 10kHz











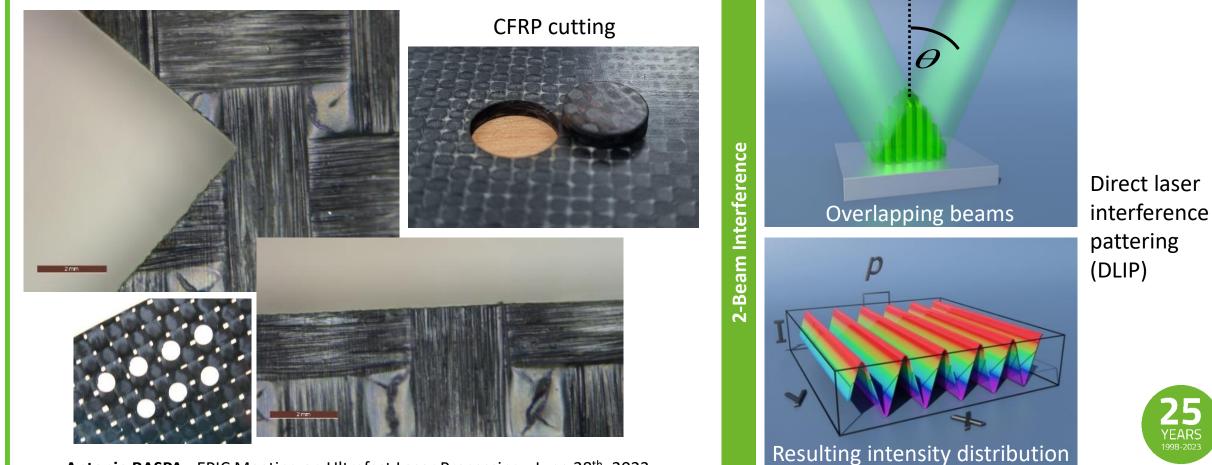
5 pulse burst at 200kHz with 600µJ burst energy





Applications

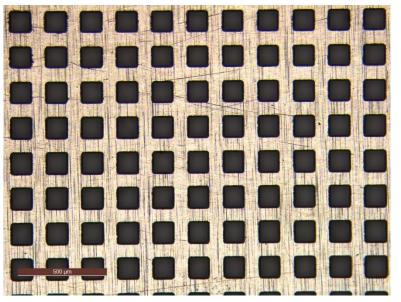
The large operational parameter space enables a wide range of applications. From glass separation to surface functionalisation, micro-welding to micro-via drilling.





Invar foil cutting

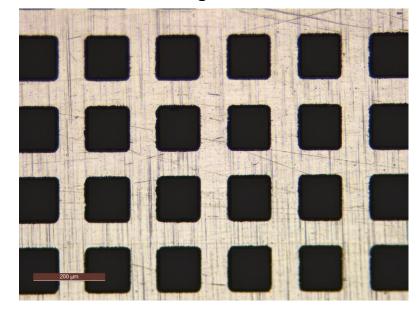
5× magnification



- 20µm thick Invar foil
- 100µm square holes, 200µm pitch
- 20MHz intra-burst pulse repetition frequency
- 16.kHz burst frequency, 10 pulses per burst
- 6µm separation between burst
- 30 passes

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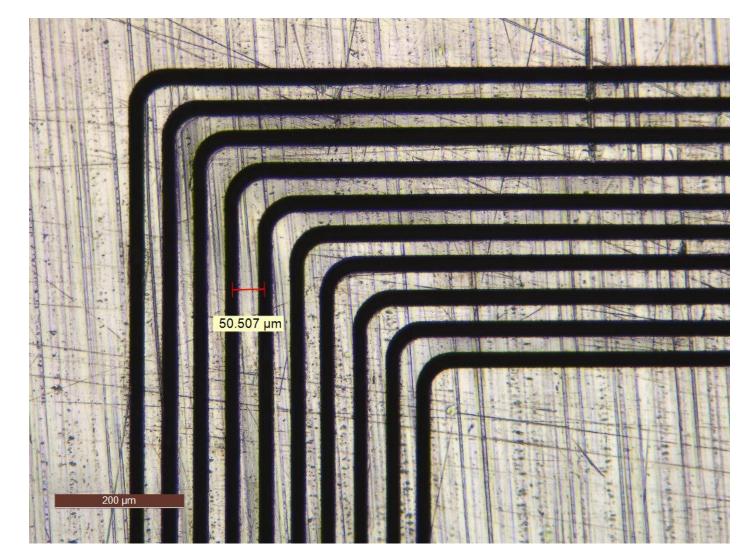
10× magnification







Foil ablation for RFID

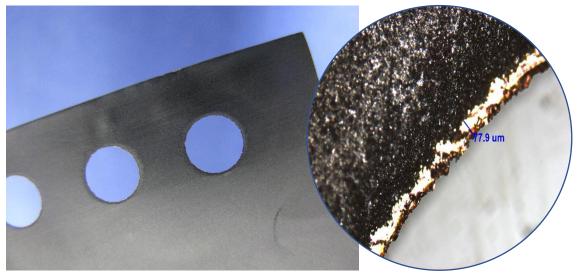






Battery electrodes slitting and notching

- Wavelength 515nm
- > Average power level 80W
- Fast-burst mode
- Galvo scanner for high-speed processing
- Feasible also with CO₂ but with copper exposed alongside the cut
- > USP GREEN laser produces higher overall cut quality



25 YEARS 1998-2023

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USP Green

VS



Applications for LXR[®] series

- High-speed separation of optically transparent materials
- Joining of optically transparent materials to similar/dissimilar materials
- Micromachining with virtually no thermal transfer
- Surface functionalisation in a range of materials for a range of applications
- Metal foil scribing/ablating
- Sub-surface glass marking
- Cutting of metal and plastics for medical devices
- Cutting carbon fibre composites
- Engraving printing drums for flexo packaging

Industries for LXR[®] series

- Mobile internet enabled devices
- Medical device manufacturing
- Microelectronics
- Micromachining
- Flat panel display cutting
- Automotive
- Printing
- Security













Thank you for your attention

ANY QUESTION?

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Ben Fulford, Rolf Birch, Sergey Kurilchik, Louise May and Jason Lee